

PTO/SB/08a (06-03)

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INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT

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## Complete If Known

Application Number	10/648,927
Filing Date	August 27, 2003
First Named Inventor	Tianhong Cui, et al
Art Unit	
Examiner Name	
Attorney Docket Number	16675/97145-00

## U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Document Number Number-Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
24		US- 5,502,667	03/26/1996	Bertin, et al	
		US- 5,563,344	10/08/1996	Kaiser, et al	
		US- 5,587,128	12/24/1996	Wilding, et al	
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## FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document Country Code <sup>2</sup> Number <sup>3</sup> Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	1 <sup>6</sup>

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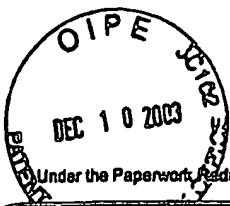
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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet **2** of **4**

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### NON PATENT LITERATURE DOCUMENTS

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W	✓	ROOS, N., LUXBACHER, T., GILSNER, T., PFEIFFER, K., SCHULZ, H. & SCHEER, H.-C.; Nanoimprint Lithography with a Commercial 4 Inch Bond System for Hot Embossing, Presented at SPIE'S Microlithography, 27-28 February 2001, Santa Clara, CA	
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	✓	BECKER, H. & HEIM, U.; Hot Embossing as a Method for the Fabrication of Polymer High Aspect Ratio Structures; Sensors and Actuators 83 (2000) pgs. 130-135	
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W	✓	LIN, L., CHIU, C., BACHER, W. & HECKELE, M.; Microfabrication Using Silicon Mold Inserts and Hot Embossing; Proceedings of the International Symposium on Micro-Machine and Human Science; 1996; pgs. 67-71	

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*N. P. Kumar*

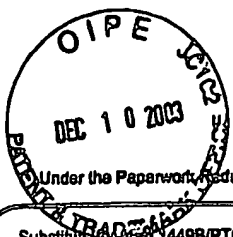
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Sheet

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**NON PATENT LITERATURE DOCUMENTS**

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2/	/	BASKI, A., ALBRECHT, T. & QUATE, C.; Tunnelling Accelerometer; Journal of Micro-Scopy, 152; pgs. 73-76, 1988	
	/	WALTMAN, S. & KAISER, W.; An Electron Tunneling Sensor; Sensors Actuators, Vol. 19; pgs. 201-210, 1989	
	/	KENNY, T., WALTMAN, S. REYNOLDS, J. & KAISER, W.; Micromachined Silicon Tunnel Sensor for Motion Detection; Appl. Phys. Lett., Vol. 58; pgs. 100-102; 1991	
	/	TANG, W., NGUYEN, T. & HOWE, R.; Laterally Driven Polysilicon Resonant Microstructures; IEEE, February 20-22, 1989, pgs. 53-59	
	/	JOHNSON, W. & WARNE, L.; Electrophysics of Micromechanical Comb Actuators; Journal of Microelectromechanical Systems, Vol. 4, 1995, pgs. 49-59	
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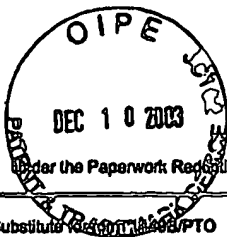
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W	1	HIRANO, T., FURUHATA, T., GABRIEL, K. & FUJITA, H.; Design, Fabrication, and Operation of Submicron Gap Comb-Drive Microactuators; Journal of Microelectromechanical Systems, Vol. 1; March 1992; pgs. 52-59	
W	1	PATTERSON, P., HAN, D., NGUYEN, H., TOSHIYOSHI, H., CHAO, R. & WU, M.; A Scanning Micromirror with Annular Comb Drive Actuation; 15th IEEE International Conference on Microelectromechanical Systems, 2002; pgs. 544-547	

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